


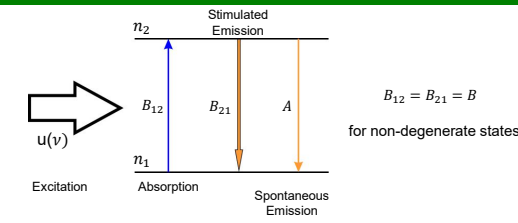
4. Nano-optics using far-field optical techniques

- 4.1 Introduction: single-molecule methods in biology
- 4.2 Single-molecule tracking (SMT)
- 4.3 Stochastic optical reconstruction microscopy (STORM)
- 4.4 4pi microscopy
- 4.5 Stimulated emission depletion (STED)
- 4.6 3D laser lithography using STED

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### Stimulated Emission




$$\dot{n}_2 = B u(\nu) n_1 - B u(\nu) n_2 - A n_2$$

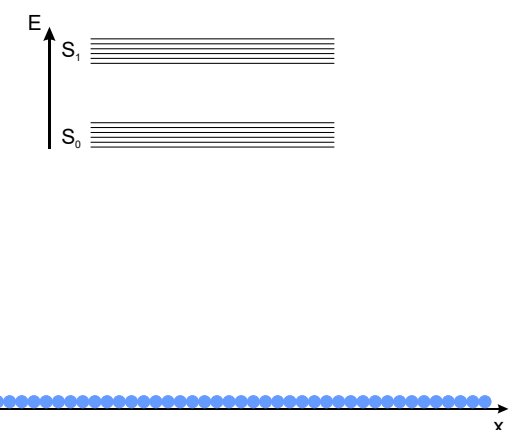
The coefficient **A** (spontaneous emission) depends on the density of states:

$$\frac{A}{8\pi \nu^2/c^3} = B \cdot h\nu$$


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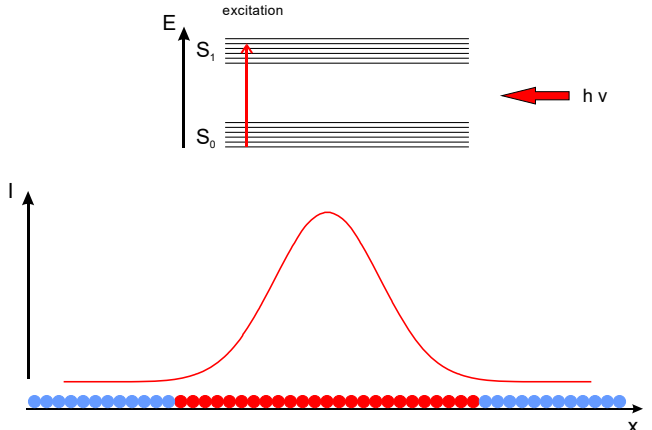
### Stimulated Emission Depletion



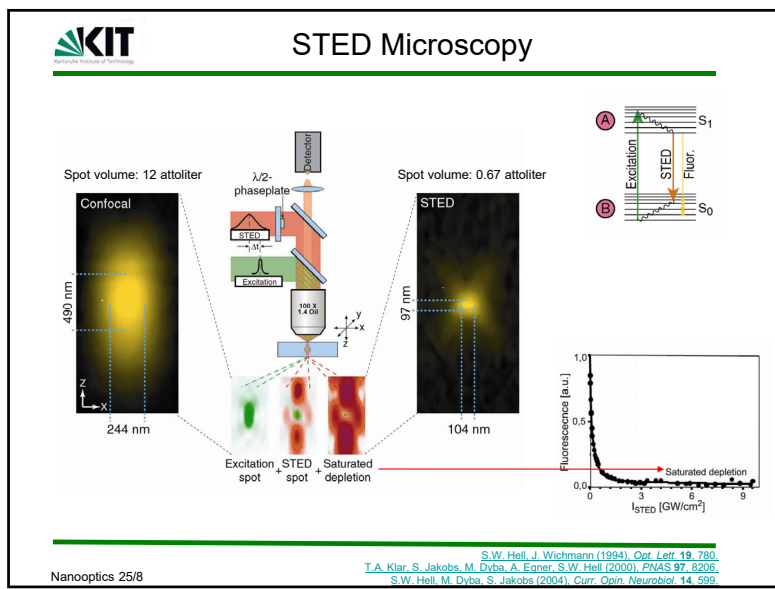
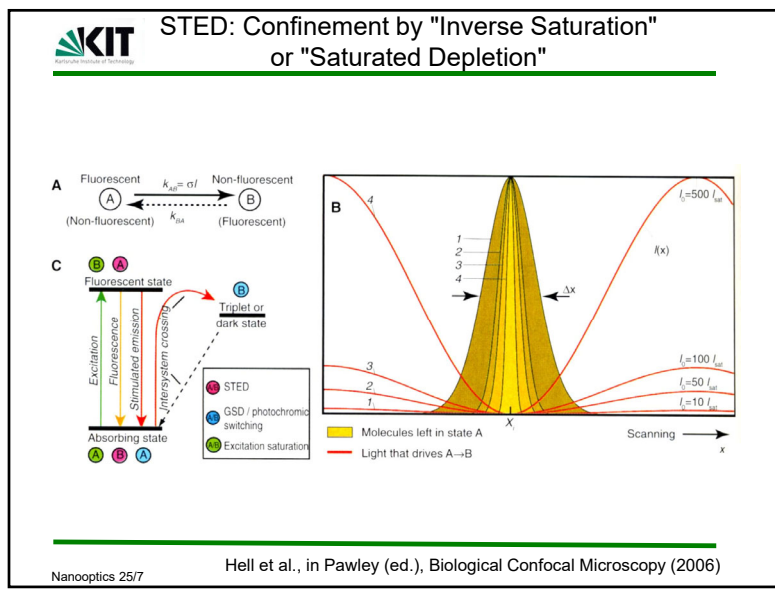
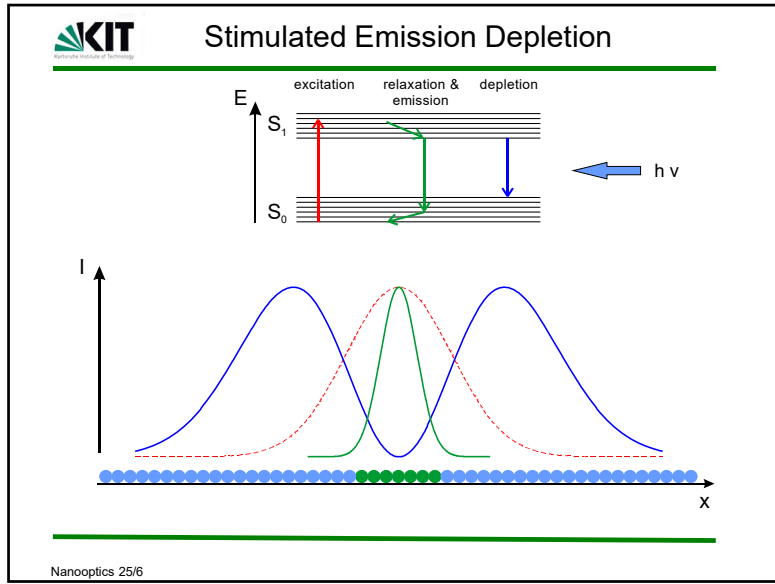
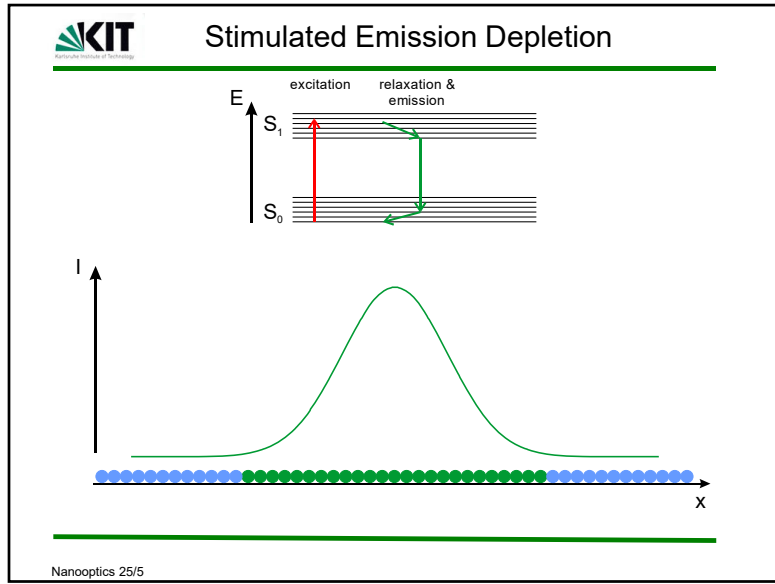
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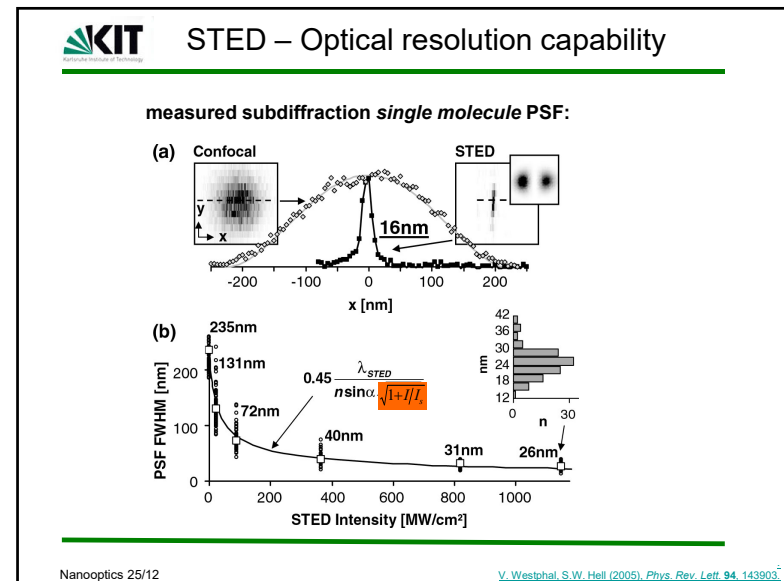
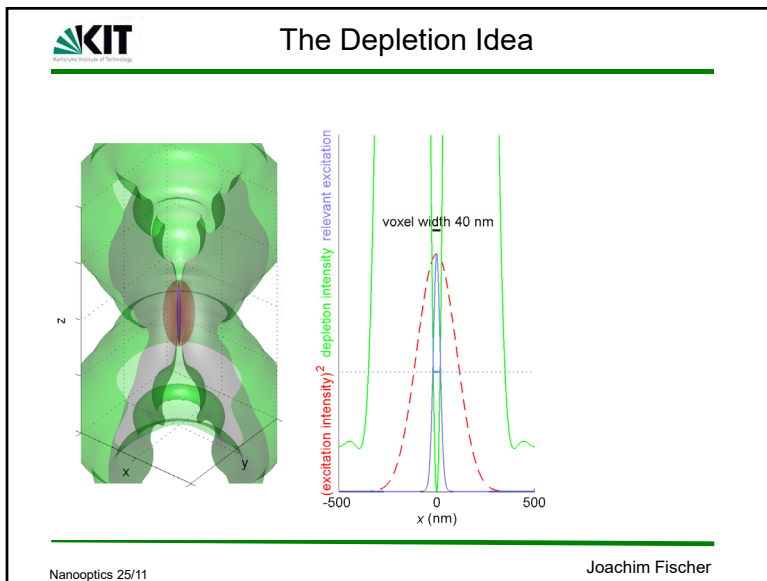
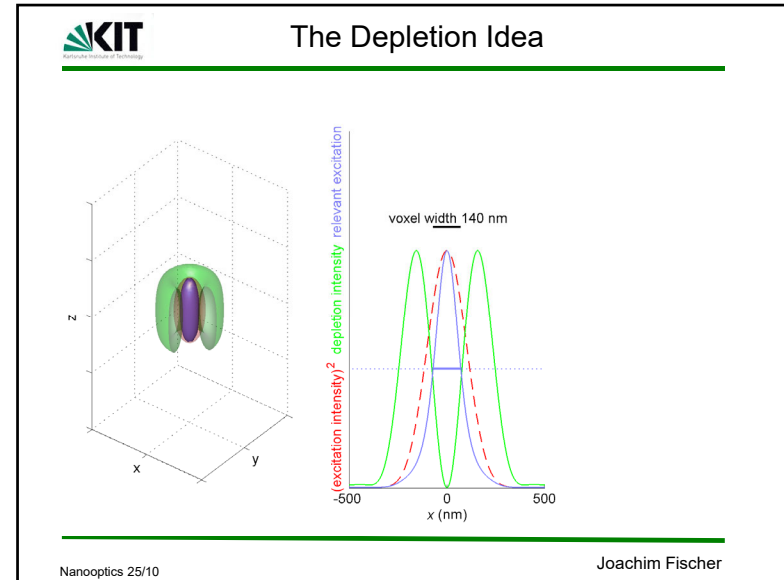
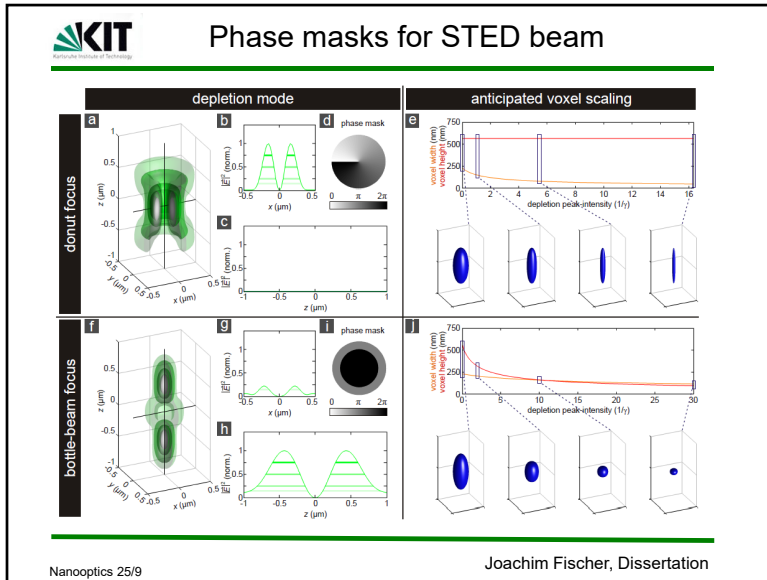


### Stimulated Emission Depletion



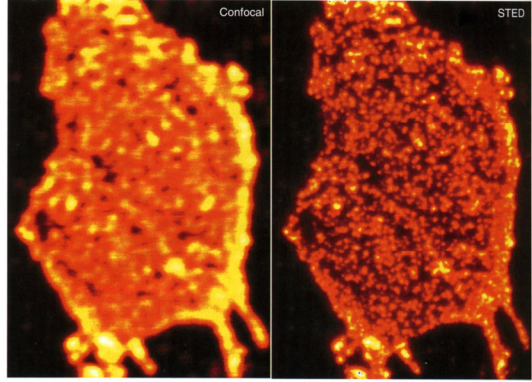
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### Comparison: Confocal microscopy and STED



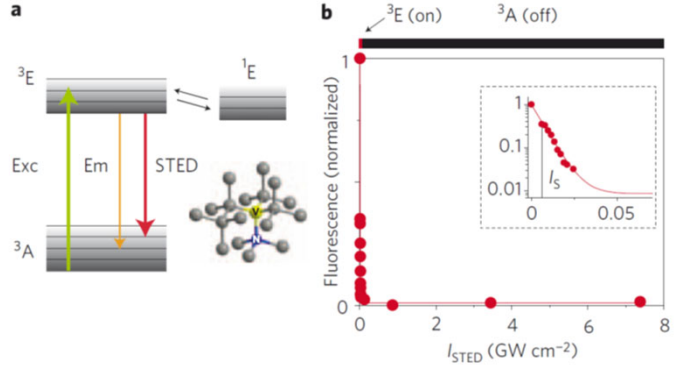
Plasma membrane patch immuno-stained against SNARE protein SNAP25; secondary antibody Atto532-NHS; STED at 615 nm (Pawley, Biological Confocal Microscopy, 2006).

Hell et al., in Pawley (ed.), Biological Confocal Microscopy (2006)

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### N-V Color-Center in Diamond

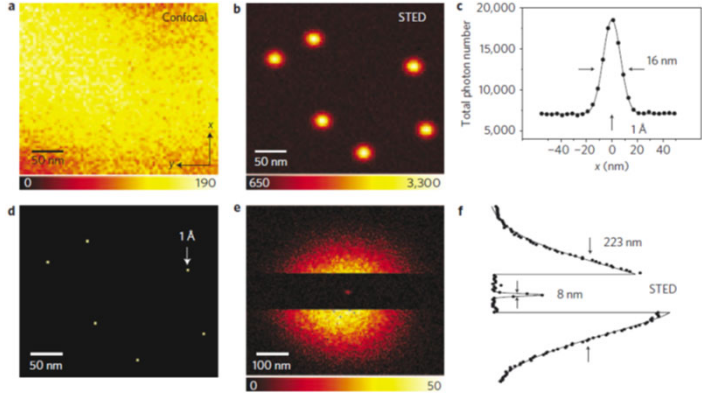


Rittweger et al., Nature Photonics (2009)

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### N-V Color-Center in Diamond

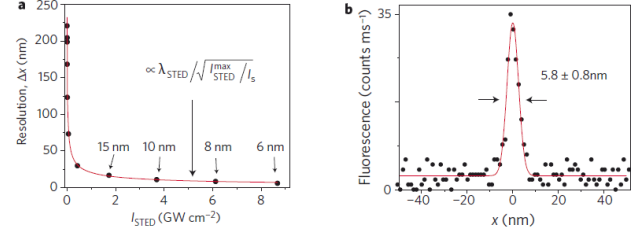


Rittweger et al., Nature Photonics (2009)

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### N-V Color-Center in Diamond



Rittweger et al., Nature Photonics (2009)

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**KIT** Motivation – 3D Direct Laser Writing

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laser beam  
femtosecond pulses

photoresist  
glass substrate

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**KIT** Motivation – 3D Direct Laser Writing

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Photonic Crystals

Optical Metamaterials

J. K. Gansel *et al.*, *Science* 325, 1513 (2009)

M. Thiel *et al.*, *Adv. Mat.* 21, 4680 (2009)

Bio Scaffolds

Mechanical Metamaterials

20  $\mu\text{m}$

F. Klein *et al.*, *Adv. Mat.* 22, 868 (2010) M. Kadic *et al.*, *Appl. Phys. Lett.* 100, 191901 (2012)

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**KIT** The Depletion Idea

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$S_1^*$

$S_1$

TPA

$S_0^*$

$S_0$

ISC

$T_1$

$R^*$

polymerization initiation

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## The Depletion Idea

$S_1^*$   
 $S_1$   
 $S_0^*$   
 $S_0$

TPA, SE, ISC,  $T_1$ ,  $R^*$ , polymerization initiation

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## STED-DLW – Setup

photo diode, piezo scanning stage, AOM, optional phase mask, excitation, Ti:Sa oscillator, 810 nm, 80 MHz, 100 fs, Nd:YAG SHG, 532 nm, cw, depletion

### Photoresist

monomer: pentaerythritol tetraacrylate (99.75% wt)  
 photoinitiator: 7-diethylamino-3-thenoylcoumarin (0.25% wt)

absorbance, fluorescence, depletion, excitation, wavelength (nm)

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## Results – Polymerization Suppression

1  $\mu$ m

J. Fischer et al., Adv. Mat. **22**, 3578 (2010)

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## Results – Lateral Linewidth & Resolution

depletion power (mW)	linewidth (nm)
0	150
10	130
20	110
30	100
40	95
50	90
60	85
70	80
80	75
100	75
130	85
160	90
210	110
270	145

155 nm, 65 nm, 100 nm

J. Fischer et al., Adv. Mat. **22**, 3578 (2010)

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